

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Jeffrey W. Carr

Appln. No.: 10/608,384

Confirm. No.: 7970

Filed: June 27, 2003

Title: Apparatus and Method for Reactive Atom
Plasma Processing for Material Deposition

PATENT APPLICATION

Art Unit: 1765

Examiner: Vinh, Lan

Docket No. RAPT-01000US4

Customer No. 23910

AMENDMENT AND REPLY TO OFFICE
ACTION UNDER 37 C.F.R. § 1.116

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

This Reply is in response to the Final Office Action dated January 5, 2007.

Amendments to the Claims are reflected in the listing of claims which begins on page 2
of this paper.

Remarks/Arguments begin on page 7 of this paper.